Surface Analysis of Nanomaterials (나노소재표면분석)

:Surface and Thin Film Analysis (표면 및 박막분석)

장소: 공과대학 6호관 510호 시간: 목 (6-A, 6-B, 7-A, 7-B, 8-A, 8-B)

Instrumentation

The primary components that make up the ESCA instrument are the vacuum system, X-ray source, electron energy analyzer, and data system.

hemispherical energy analyzer computer control and data acquisition multi-channel detector plate electron lens crystal X-rav monochromator variable aperture electron flood gun 600 X-ray (charge anode neutralizer) (AI) ample sample motorized stage stage manipulator electron gun ultrahigh vacuum chamber sample entry and preparation chamber UHV pump

A schematic diagram of an ESCA spectrometer using a monochromatized X-ray source

Instrumentation

Example

K-Alpha



ESCALAB 250



Instrumentation

Vacuum for ESCA analysis

The ESCA experiment must be conducted under vacuum for three reasons

- First, the emitted photoelectrons must be able to travel from the sample through the analyzer to the detectorwithout collidingwith gas phasemolecules.

 \rightarrow [10⁻⁶-10⁻⁷ torr; 1 torr = 133 Pa]

- Second, some components such as the X-ray source require vacuum conditions to remain operational.

 \longrightarrow [10⁻⁶-10⁻⁷ torr; 1 torr = 133 Pa]

- Third, the surface composition of the sample under investigation must not change during the ESCA experiment.

The actual vacuum required will depend on the reactivity of the sample (e.g. metallic Na will require a better vacuum than PTFE). For most applications a vacuum of 10⁻¹⁰ torr is adequate. For studies on polymeric materials, good results can usually be obtained with a vacuum of 10⁻⁹ torr.

Instrumentation

Sample loading

- Samples are typically introduced into the analysis vacuum chamber via a load-lock or preparation chamber

- The load-lock is a small volume chamber that can be isolated from the analytical chamber and then backfilled to atmospheric pressure

- Sample manipulators typically have the capability to translate a sample in three directions and to rotate it in one or two directions.

- By coupling different sample mounting techniques with the manipulator capabilities and/or adding other components such as ion guns, a range of different ESCA experiments can be done (variable temperature, variable angle, multisample, destructive depth profiling, etc.).

Instrumentation

X-ray Source

- X-rays for an ESCA experiment are usually produced by impinging a high-energy (~10 keV) electron beam onto a target.

- Common anodes along with the energies of their characteristic emission lines are listed in Table (below)

Anode material	Emission line	Energy (eV)	Width (eV)
Mg Al Si Zr Ag Ti Cr	Κα Κα Κα Lα Κα Κα	1253.6 1486.6 1739.5 2042.4 2984 4510 5415	0.7 0.85 1.0 1.7 2.6 2.0 2.1

Instrumentation

X-ray Source

- A multi-anode configuration is used to provide two or more X-ray energies. Most spectrometers use only one or two anodes, with AI and Mg the most common for non-monochromatic sources and AI the most common for monochromatic sources.
- Since most of the incident electron energy is converted into heat, anodes are usuallywater cooled. This allows operation at higher power loads without significant degradation (e.g. melting).
- The best way to optimize single energy production is to use an X-ray monochromator. The most popular monochromatized source combines an Al anode with one or more quartz crystals.



Instrumentation

X-ray Source

- Most non-monchromatized sources illuminate a spot that is a few centimeters in diameter.

- In contrast, the monochromatized sources typically illuminate an area that is a few millimeters or smaller in diameter.

- With a focused electron gun and the quartz crystal used as both a **monochromator** and a focusing element, **spot sizes <50 µm in diameter** can be realized

- When used with a suitable monochromator, **synchrotron radiation** can provide a tunable source of high intensity, focused X-rays for photoemission experiments. With the use of zone plates **X-ray spot sizes <150nm** can be obtained

Instrumentation

Analyzers

The analyzer system consists of three components:

- 1. the collection lens
- 2. the energy analyzer
- 3. the detector
- 1. the collection lens

 On most modern ESCA spectrometers, the lens system can collect photoelectrons from solid angles >20. The higher the collection solid angle, the higher the number of photoelectrons collected per incident X-ray, which is generally advantageous.

- The increased collection angle is particularly important for samples that degrade upon exposure to X-rays, since the more efficient the detection system is (e.g. the more photoelectrons collected per X-ray) the more data that can be collected before the sample is damaged.



Instrumentation

Analyzers

2. the energy analyzer

The most common type of energy analyzer used for ESCA experiments is the electrostatic hemispherical analyzer

It consists of two concentric hemispheres of radius R_1 and R_2 .

A potential of *V* is placed across the hemispheres such that the outer hemisphere is negative and the inner hemisphere is positive with respect to the potential at the center line, $R_0 = (R_1 + R_2)/2$. The center line potential is known as the pass energy $F = \frac{1}{1000}$

Concentric hemispherical analyzer (CHA)

Instrumentation

Analyzers

2. the energy analyzer

pass energy

The center line potential is known as the pass energy. As noted previously, most ESCA experiments use a constant pass energy. This will maintain a constant absolute resolution, ΔE , for all photoelectron peaks, since the analyzer resolution is defined as $\Delta E/E$, where *E* is the energy of the electron as it passes through the analyzer

-> the signal intensity will also decrease at smaller pass energies

Instrumentation

Analyzers

2. the energy analyzer



PET : Polyethylene terephthalate

Instrumentation

Analyzers

3. Detector

- Since the electrons arrive at the analyzer exit with a range of energies, the most efficient means of detection is to use a multichannel array to count the number of electrons leaving the analyzer at each energy.



In both diagrams the analyzer pass energy is set to transmit electrons with a KE of 50 eV after retardation to the detector

Instrumentation

Analyzers

3. Detector



 The lens system in Figure (left) is set so only photoelectrons with KEs greater than 100 eV will be allowed into the analyzer and retarded.

-If a 150 eV photoelectron enters the lens it will be retarded to a KE of 50 eV, pass through the analyzer and strike the detector.

-Photoelectrons with KEs significantly great than 150 eV will pass through retardation lenses and strike the outer hemisphere of the analyzer since their KE after retardation in the lens is still greater than the 50 eV pass energy.

 Likewise photoelectrons with KEs significantly less than 150 eV, but still greater than 100 eV, will pass through the lenses and strike the inner hemisphere of the analyzer since their KE after retardation in the lenses is less than the 50 eV pass energy.



In both diagrams the analyzer pass energy is set to transmit electrons with a KE of 50 eV after retardation to the detector

Instrumentation

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Analyzers

3. Detector



- The lens setup has been changed so now only photoelectrons with KEs greater than 120 eV will be allowed into the analyzer and retarded.

-The 150 eV photoelectron will still pass through the lenses and be retarded.

- -However, after retardation its KE will be significantly lower than 50 eV and it will strike the inner hemisphere.
- -In Figure 3(left) photoelectrons with an initial KE of 170 eV will be passed through the lenses and be retarded to 50eV so they can pass through the analyzer.
- The higher energy photoelectrons (e.g. 190 eV) will pass through the lenses, but after retardation will still have KEs greater than 50 eV and will strike the outer hemisphere.

Spectral Quality

- The signal-to-noise (S/N) ratio and resolution are the most important properties to consider when evaluating spectral quality.

- The length of time it takes to reach a given S/N ratio at a given energy resolution is the important criterion

- The $\mathcal{S}/\!N$ of a spectrum can be increased by either increasing the scan time or decreasing the energy resolution



Figure 3.17 The (a) C_{1s} and (b) noise spectra from a graphite sample. The data in each region were acquired with the same scan parameters (time, eV/point, window, pass energy, etc.). These data, obtained after three minutes of scanning, have a peak-to-peak signal-to-noise ratio of 575 at an energy resolution of 0.65 eV

Depth Profiling

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- The sampling depth of ESCA is 10 nm and the atomic dimensions are 0.3 nm, then the surface region could be composed of \sim 30 atomic layers.

- The ESCA spectrum we obtain will be a **convolution** of the information from all the layers



Depth Profiling

- The ESCA spectrum we obtain will be a **convolution** of the information from all the layers



Depth Profiling

Conventional Depth profiling



Depth Profiling

Applied Na

Conventional Depth profiling



evices LAB.

- Use of an ion gun to erode the sample surface and re-analyse
- Enables layered structures to be investigated
- Investigations of interfaces
- Depth resolution improved by:
 - Low beam energies
 - Small ion beam sizes
 - Sample rotation

Depth Profiling

Conventional Depth profiling



Calibration of depth scale

- 1. Sputtering rate determined from the time required to sputter through a layer of the same material of known thickness.
- 2. After the sputtering analysis, the crater depth is measured using depth profilometer. A constant sputtering rate is assumes.

Depth Profiling

Conventional Depth profiling



- Hard Disc Depth Profile:
 - Argon lons
 - Low energy (1 keV)
 - Azimuthal Rotation
 - Non-linear Least Squares Fitting



Depth Profiling

Angular dependent ESCA

- As the sample angle to the analyzer entrance is increased, with the X-ray source and the analyzer kept in a fixed position, the photoelectrons originate from an increasingly surface localized zone



The sample angle, θ , is defined relative to the normal to the surface

- If data are acquired at photoelectron take-off angles of, for example, 0, 50, and 80 from the surface normal, three sets of ESCA data can be obtained that contain information about the composition as a function of depth.

Depth Profiling

Angular dependent ESCA

- The shape of this composition versus take-off angle curve can reveal much about the compositional organization of a surface

Table 3.12	Angular dependent ESCA data from
a fluorine-c	ontaining polyetherurethane (normal-
ized signal	intensities) ^a

Angle (degrees)	С	Ο	Ν	F
0	5456	1267	189	236
39	4341	979	118	157
55	3498	822	103	126
68	2736	642	68	70
80	1706	395	34	39

- For accurate and meaningful depth profiles from angular dependent ESCA data, we assume that the surfaces and interfaces studied are molecularly smooth and that overlayers are of uniform thickness

Depth Profiling

Angular dependent ESCA



(c) Because <u>the ratio of</u> <u>intensities does not change with</u> <u>sample angle</u>, for a sample homogeneous in depth, a plot of the ratio of photoemission intensities (or the ratio of atomic percents) with sample angle will show zero slope

(f) a plot of <u>the ratio of the red</u> <u>atom photoemission intensity to</u> <u>the blue atom photoemission</u> <u>intensity with sample angle will</u> <u>increase in an exponential</u> <u>fashion with sample angle</u>. The photoemission from the blue atoms will decrease in intensity with increasing sample angle

Depth Profiling

Angular dependent ESCA



Depth Profiling

Angular dependent ESCA



Depth Profiling

Angular dependent ESCA

Example. Silicon wafer



- Full Range of angles collected simultaneously

- User selectable angle resolution (<=96 channels)



X-Y Mapping and Imaging

Parallel Imaging

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- A method for image collection in which, at any given moment, data are collected from the entire field of view at a single energy

• Spectrum Acquisition



Image Acquisition



e.g. Parallel Imaging - ESCALAB 250

X-Y Mapping and Imaging

Parallel Imaging



Flood Source Image Real Time



Au 4f Image – 10 minutes Applied Nanomaterials & Devices LAB. Electronics & Probes by Materials Engineering



Au 4f Image - 6 seconds





Au 4f Image - 60 seconds

- Gold Tracks on Silicon
- Monochromated X-ray Source

X-Y Mapping and Imaging

Parallel Imaging

Wide Magnification Range 4 mm - 120 µm

4 mm 120 µm 1 mm and overlay of 15 µm lens defined micro-area

250 µm

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X-Y Mapping and Imaging

Stage Mapping



- Ultimate resolution
 - ~15 µm
- Field of View
 - ∼1.5 mm x 0.4 mm
- Note
 - As the beam is scanned in the dispersive direction the X-ray energy and intensity changes - must be corrected in software.

X-Y Mapping and Imaging

Stage Mapping

- Mixed Al₂O₃ HfO₂ layer deliberately grown to be non-uniform and mapped by XPS
- 379 Point Map from 200 mm Wafer



Si 2p Elemental





X-Y Mapping and Imaging

Comparison of Imaging Methods

	Parallel Imaging	Scanning Mono	Scanning Stage
Resolution	<3 µm	<15 μm	<15 µm
Field of View	120 µm to 4 mm	1.5 mm x 0.4 mm	Up to 300 mm
Speed	Fast	Medium	Slow
Additional Information	None	32 Channel snapshot	112 Channel snapshot 96 Channel ARXPS

X-Y Mapping and Imaging

Advantages of Stage Mapping

- Spatial resolution is determined only by the X-ray spot size
 - Constant throughout the acquisition
 - No degradation of the image quality at the edges
- Spectrum at every pixel allows
 - High-quality chemical state maps
 - Quantitative imaging
 - Thickness maps
- The spatial resolution is independent of the settings of the transfer lens
 - The spectrometer is always operated at its maximum transmission.
- The point on the sample being mapped is always in the optimum analysis position
 - There can be no changes in the sensitivity over the field of view.
- X-ray energy and intensity independent of position on the sample
 No software corrections required
- Very large field of view possible (up to 60 x 60 mm for K-Alpha).

X-Y Mapping and Imaging

Examples

Al wire_XPS mapping



X-ray size	: 200 µm	
Area	: 2 mm × 2 mm	
Step size	: 50 µm	
Point count	:1681 (41 × 41)	
# of frames	: 3	
Time per Frames : 1 s		
Center/Width		
- Al2p	: 73.5 / 2 eV	
- 01s	:531 / 3 eV	
- C1s	:283.5 / 2 eV	





Binding Energy (eV)





X-Y Mapping and Imaging

Examples



Ag wire_XPS mapping



<Homework>

- 1. Plot XPS spectra of CsPbBr₃ on Gold foil
- 2. Deconvolute multiple peaks
- 3. Analysis atomic percentage
- <Due date> 12th May / e-mail

<Reference>

- 1. Down load fitting program and raw data at APPND website
- 2. Watch follow link

https://www.youtube.com/watch?v=do1ZZP3yDrl

About Presentation

- 1. Presentation date
 - -> 28th April (5 students)/ 12th May (5 students)
- 2. How long?
 - -> 20 min long
- 3. Language
 - -> Prefer English but Korean is also OK.

4. Subject and guideline

-> All about XPS analysis that is <u>related to your research topic</u>.

Please make your own presentation materials. Put introduction, how important it is, what and what kind of meaningful information they (when you review a paper) or you can get from the XPS analysis?, You can use your own data or review any paper that you have impressed.

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